
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Wu et al.

Application No.: 10/820,525

Filed: April 7, 2004

Title: METHODS FOR PRODUCING LOW-K
CDO FILMS WITH LOW RESIDUAL
STRESS

Attorney Docket No.:
NOVLP091/NVLS-2889

Examiner: Maldonado, Julio J.

Group: 2823

Confirmation No: 8337

CERTIFICATE OF EFS-WEB TRANSMISSION

I hereby certify that this correspondence is being transmitted electronically through EFS-WEB to Mail Stop AF, Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450 on March 4, 2009.

Signed: /Latonia Ervin/
Latonia Ervin

AMENDMENT E

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action dated December 4, 2008 in the above-identified application, please amend the application as follows:

Amendments to the Claims are reflected in the listing of claims that begins on page 2 of this paper.

Remarks/Arguments are on page 7 of this paper.

A **Declaration under 37 CFR 1.131** of the inventors, with attached Exhibits A - H, accompanies this paper.